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Introduction

This is the second year that the Optical Systems Alignment and Tolerancing Conference at the SPIE Optics and Photonics Symposium has been offered. The conference this year has again been a success, with strong papers and presentations on a wide variety of topics.

The topics of tolerancing and alignment continue to play crucial roles in the development and production of optical systems. The topics are closely related and very timely as current technology is forging ahead with new methods, novel systems, and increasingly challenging requirements for a number of applications. Tolerancing and alignment are growing topics that will continue to play key roles for the success of such systems.

The Optical Systems Alignment and Tolerancing Conference intends to provide a forum where past and current knowledge about optical alignment and tolerancing is discussed. Topics include methods, applications, algorithms, and hardware related to alignment and tolerancing. In this second year, we have continued to have a variety of papers from traditional applications, mathematics, and methods, to fundamental properties of light and physical optics phenomena. The conference continued its perceived useful value with positive feedback from the audience. The reader can browse and read the papers in this volume to benefit from the expertise brought to bear by the authors. We thank everyone who has made this conference a success in its second year: the authors, audience, committee, and SPIE.

Next year we will add the topic of verification, which is essential for many types of systems. Verification of optical system performance and methodologies is also a subject closely related to alignment and tolerancing. Hence, it fits well with the current program and deserves a place in the conference. Please look for Optical Systems Alignment, Tolerancing, and Verification Conferences in the future. We look forward to next year's conference being a continued success.

José M. Sasian Richard N. Youngworth